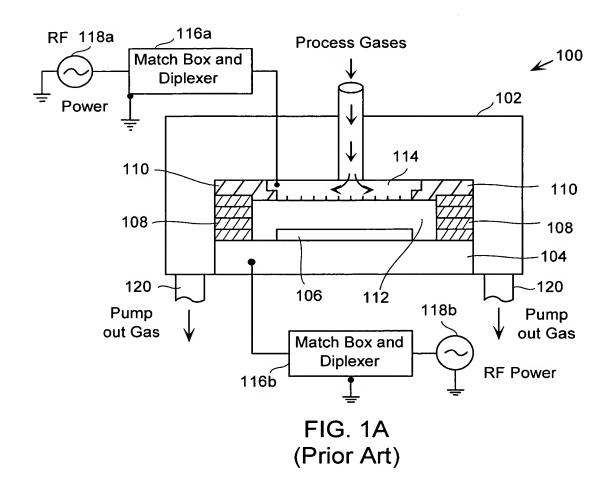
Application No: Unknown



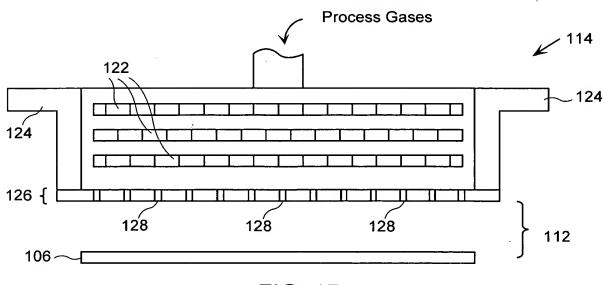
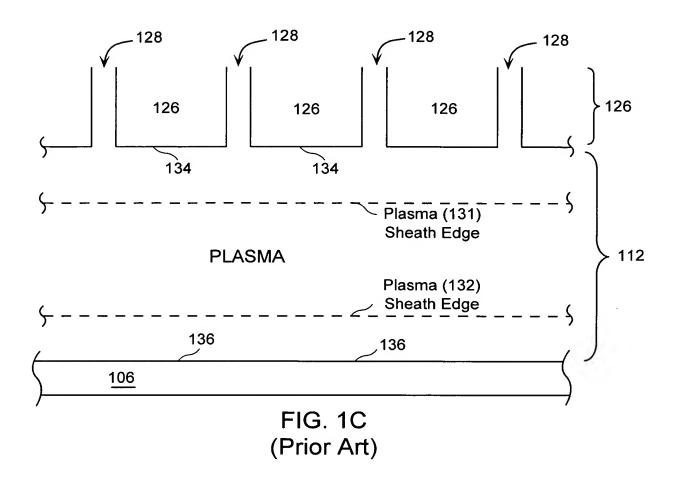
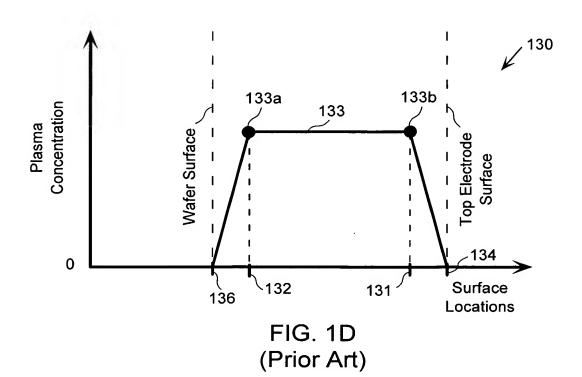


FIG. 1B (Prior Art)





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Inventors: KUTHI et al. Application No: Unknown

Attorney Docket No: LAM1P077A2

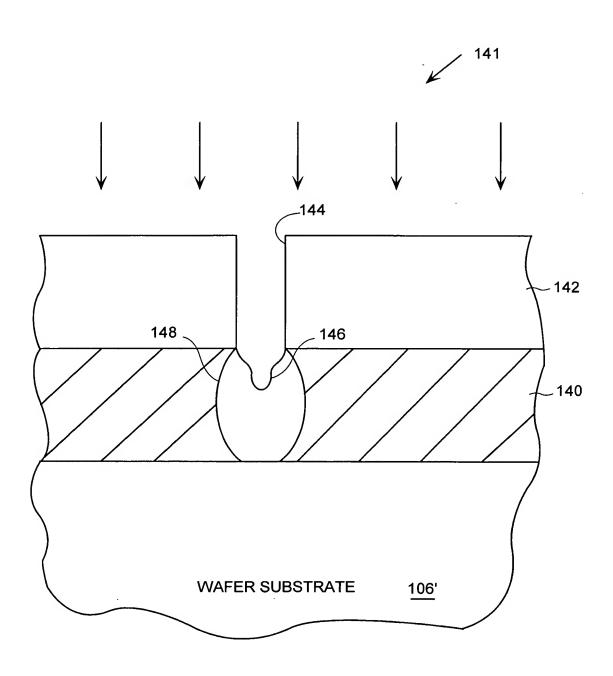
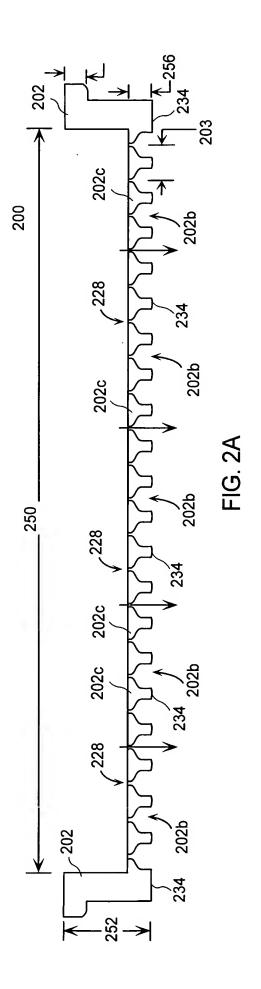
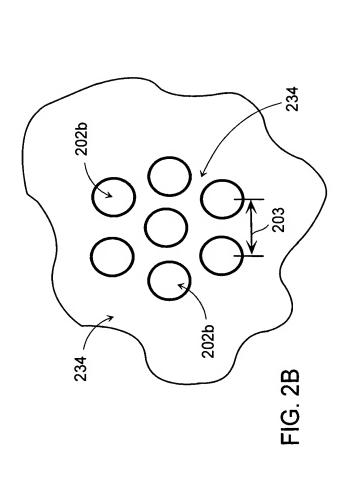


FIG. 1E (Prior Art)





Application No: Unknown

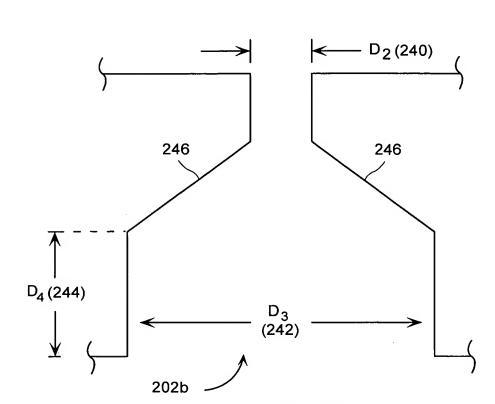


FIG. 2C

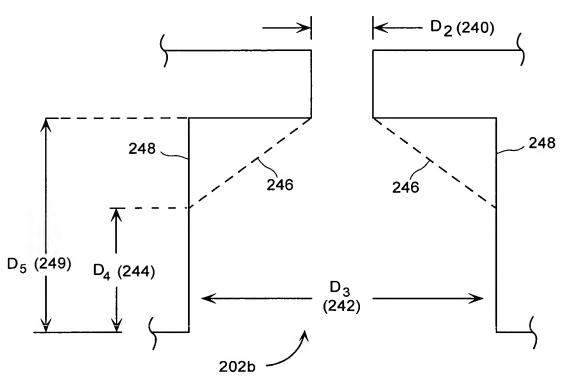


FIG. 2D

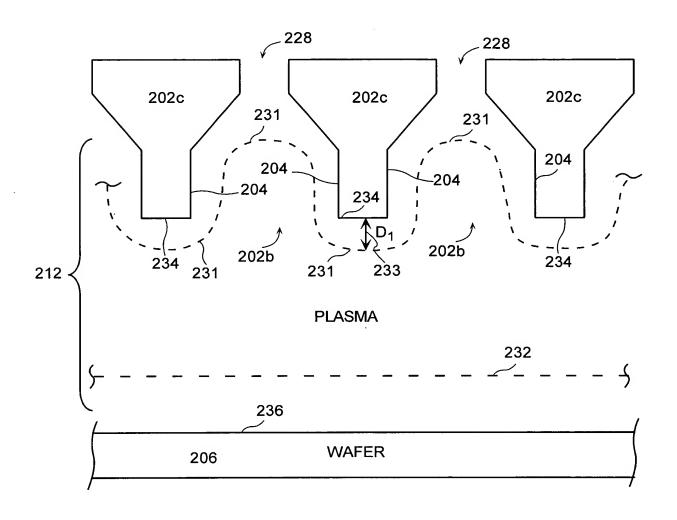
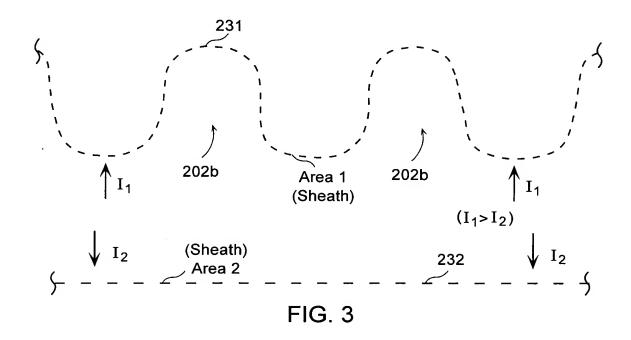
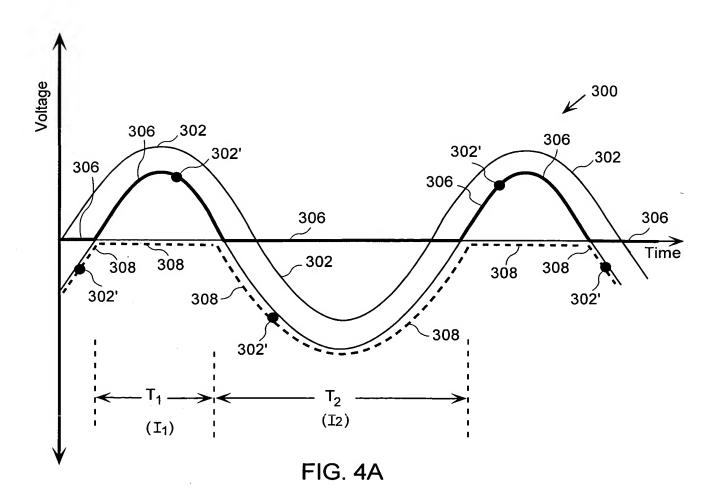


FIG. 2E





Title: SEMICONDUCTOR PROCESS CHAMBER ELECTRODE
Application No: Unknown Attorney Docket No: LAM1P077A2

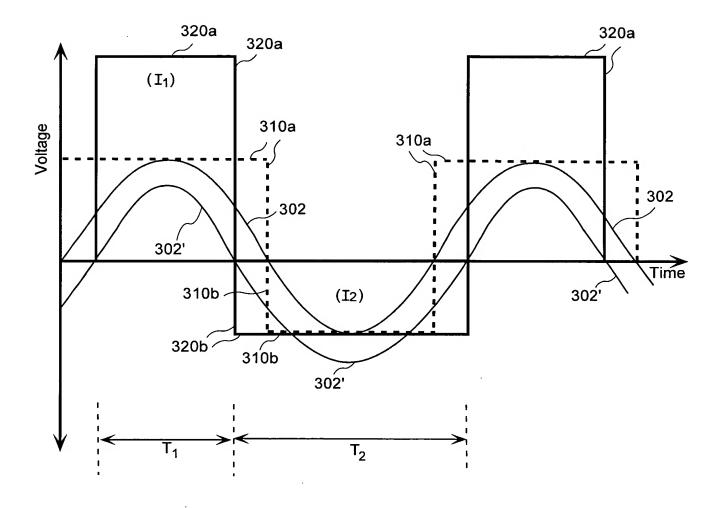


FIG. 4B

Application No: Unknown

Attorney Docket No: LAM1P077A2

Bias vs. Area Ratio

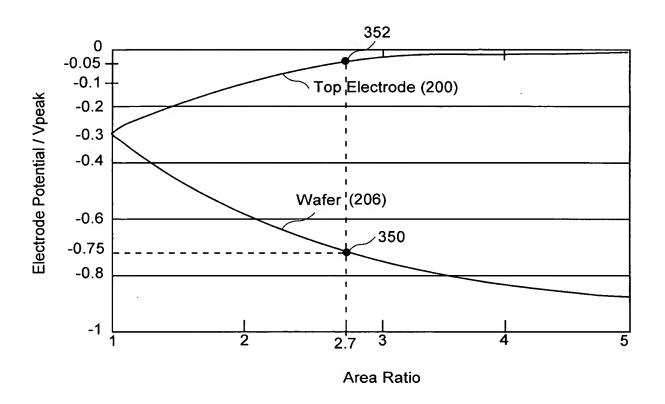


FIG. 5